Session Title:	[MF2] Frontier Metrology and Modeling II
Session Date:	November 20 (Mon.), 2023
Session Time:	14:55-16:25
Session Room:	Room F (Sicily Room, 1F)
Session Chair:	Prof. Jun Ho Lee (Kongju Nat'l Univ., Korea)

[MF2-1] [Invited] 14:55-15:25

3D Gray Level Index for Pattern Depth Monitoring Using SEM Image

Hyeon Bo Shim, Jaehyung Ahn, Inseok Park, Souk Kim, and Younghoon Sohn (Samsung Electronics Co., Ltd., Korea)

[MF2-2] [Invited] 15:25-15:55

MI's Direction for Next Journey

Byoungho Lee (Hitachi High-tech Corp., Japan)

[MF2-3] [Invited] 15:55-16:25

Local Probe Microscopy: A Potential Tool for Material Characterization at Nanoscale

Mohit Kumar (Ajou Univ., Korea)